



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:			)	CONFIRMATION NO. 5926		
Ken	suke	FUJIWARA	)			
Serial No.	:	09/280,518	)	Art Unit:	2861	
Filed	:	April 5, 1999	)	Examiner:	Hai Chi PHAM	
For	:	LASER INTENSITY ADJUSTING METHOD				

## **AMENDMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

The Examiner has re-opened prosecution in this application. A response to the Office Action dated February 4, 2005 was due by May 4, 2005. A Petition for Extension of Time (one month, large entity) is enclosed, extending the date to June 6, 2005 (June 4, 2005 being a Saturday). A check including payment of the requisite fee also is enclosed. Therefore, please accept this Amendment as timely filed and fully responsive.

In response to the Office Action dated February 4, 2005, kindly amend the aboveidentified patent application as set forth below.